EXHIBIT E



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(12) United States Patent

Choo et al.

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(54) CONCURRENT MEASUREMENT OF CRITICAL DIMENSION AND OVERLAY IN SEMICONDUCTOR MANUFACTURING

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U.S.C. 154(b) by 433 days.

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(51) **Int. Cl. G06F 17/50** (2006.01)

(52) **U.S. Cl.** **716/4**; 716/19; 716/21

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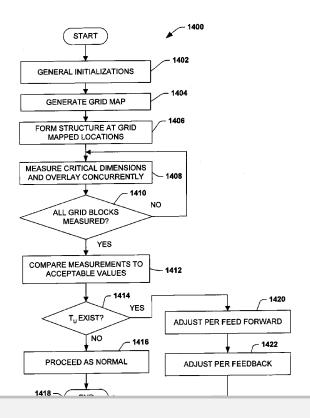
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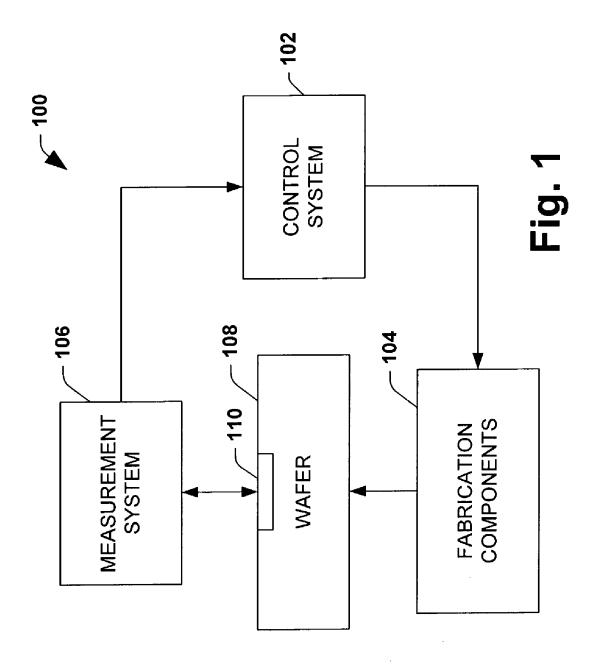
(57) ABSTRACT

A system and methodology are disclosed for monitoring and controlling a semiconductor fabrication process. One or more structures formed on a wafer matriculating through the process facilitate concurrent measurement of critical dimensions and overlay via scatterometry or a scanning electron microscope (SEM). The concurrent measurements mitigate fabrication inefficiencies, thereby reducing time and real estate required for the fabrication process. The measurements can be utilized to generate feedback and/or feedforward data to selectively control one or more fabrication components and/or operating parameters associated therewith to achieve desired critical dimensions and to mitigate overlay error.

25 Claims, 18 Drawing Sheets







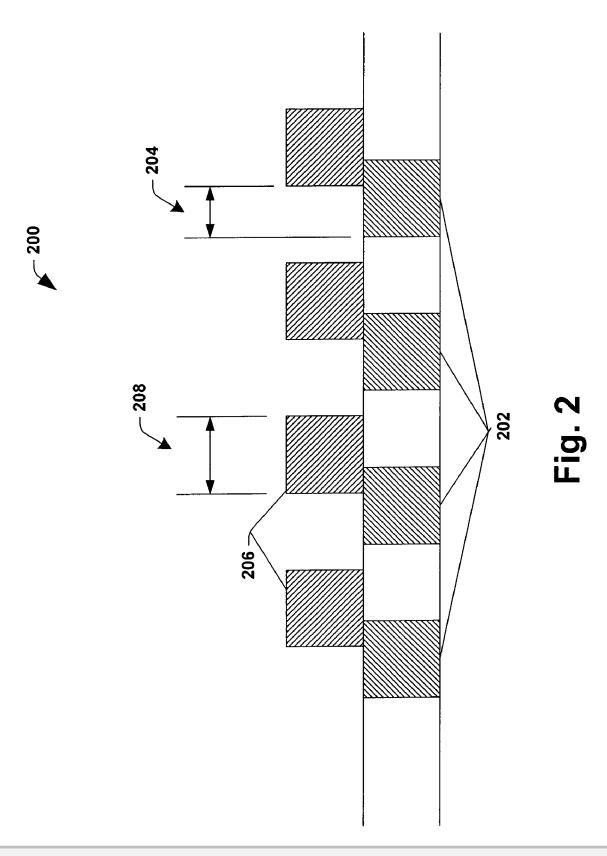


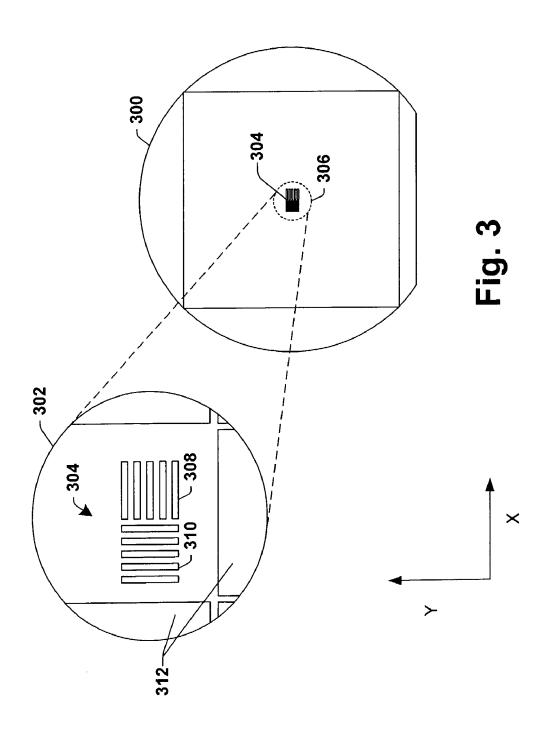
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